

# Single Wafer Cleaning Hood



## *Basic Specifications*

Wafer	φ300 mm, φ200mm , φ150mm
Carrying Cassette	Standard cassette / Open Cassette / FOUP
Processing Cassette	None
Number of Wafers	1 wafer/batch
Chemical tanks	Mixed Chemical (Dip), HF, O <sub>3</sub> (Spin)
Dryer	Spin processor
Operation	Full automatic / Semi automatic